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## Patent Abstracts of Japan

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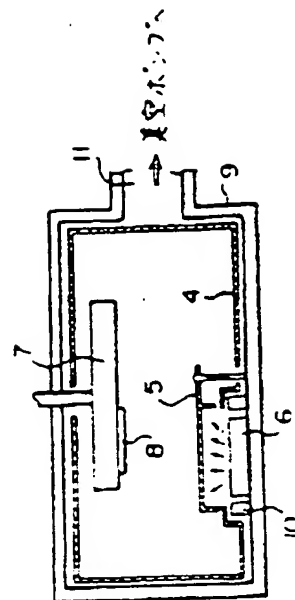
APPLICATION DATE : 15-12-87  
APPLICATION NUMBER : 62315219

APPLICANT : CANON INC;

INVENTOR : MOTOMIYA KAZUOKI;

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TITLE : DEPOSITED FILM FORMING DEVICE



ABSTRACT : PURPOSE: To reduce the frequency of the cleaning of a shield member by forming a metal layer highly adhesive to the shield member and deposited film material and liberating only a small amt. of gas on the surface of the shield member for preventing the deposition of the film material.

CONSTITUTION: The surfaces of the shield members 1 such as a deposition preventing plate 4 and a shutter 5 are sandblasted, and then cleaned with a solvent, etc., before use. The metal layer 2 is formed of the surfaces of the members 1 on which a film is deposited in a vapor-deposition device or a sputtering device. The members are set in the deposited film forming device, and a desired deposited film is laminated on a substrate. Although a deposited film 3 is also laminated on the metal layer 2, the deposited film 3 is formed with good adhesion on the metal layer 2 closely attached to the member 1, and the thickness of the film to be released can be increased. Accordingly, the frequency of the cleaning of the member 1 is reduced, and loss of time in the film forming stage can be reduced. Al, Cr, copper, etc., can be exemplified as the metal for the layer 2.

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